



Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 202450US0	SERIAL NO. 09/770,289	
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT Atsushi SHIOTA, et al.				
		FILING DATE January 29, 2001		GROUP 1712		
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
	AL					
	AM					
	AN					
FOREIGN PATENT DOCUMENTS						
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
	AO	WO 99/36953	7/22/99	WIPO	YES	NO
<i>MF</i>	AP	WO 97/00535	1/3/97	WIPO		
<i>MF</i>	AQ	EP 1 050 601	11/8/00	EP		
<i>MF</i>	AR	EP 0 921 561	6/9/99	EP		
	AS					
	AT					
	AU					
	AV					
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)						
<i>MF</i>	AW	MCCLATCHIE, S. et al. "Low Dielectric Constant Oxide Films Deposited Using CVD Techniques", Dumic Conference Proceedings, February 1998, pages 311-318.				
	AX					
	AY					
	AZ	<input type="checkbox"/> Additional References sheet(s) attached				
Examiner	<i>Mehdi Ory</i>			Date Considered <i>9/15/04</i>		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						